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CONTROL STRATEGY; REFERENCES
CHAPTER 6 - DESIGN AND DEVELOPMENTS OF
MICROTOOLS INTRODUCTION; 6.1 TYPES OF EMM TOOLS; 6.2
MICROTOOL DESIGN FOR EMM; 6.3 METHODS OF MICROTOOL
FABRICATION; 6.4 EMM FOR MICROTOOL FABRICATION; 6.5 DIFFERENT
FEATURES OF MICROTOOLS FABRICATED BY EMM; REFERENCES;
CHAPTER 7 - INFLUENCING FACTORS OF EMM; INTRODUCTION; 7.1
EMM POWER SUPPLY; 7.2 ELECTROLYTE FOR EMM; 7.3 INFLUENCE OF
IEG; 7.4 INFLUENCE OF TEMPERATURE, CONCENTRATION, AND
ELECTROLYTE FLOW; 7.5 INFLUENCE OF TOOL FEED RATE; REFERENCES;
CHAPTER 8 - IMPROVEMENT OF MACHINING ACCURACY;
INTRODUCTION; 8.1 TOOL INSULATION
8.2 ELECTROLYTE CIRCULATION
8.3 SHAPE OF THE MICROTOOL; 8.4
TOOL MOVEMENT STRATEGY; 8.5 STRAY CURRENT AND MICROSPARKS
PHENOMENA IN EMM; 8.6 HYBRID EMM; 8.7 SELECTION OF
COMBINATION OF MACHINING PARAMETERS; REFERENCES; CHAPTER 9 -
ADVANTAGES, LIMITATIONS, AND APPLICATIONS OF EMM;
INTRODUCTION; 9.1 ADVANTAGES; 9.2 APPLICATIONS; 9.3
LIMITATIONS AND REMEDIES; REFERENCES; CHAPTER 10 -
MICRODEVICES FABRICATION FOR MICROELECTROMECHANICAL
SYSTEMS AND OTHER MICROENGINEERING APPLICATIONS;
INTRODUCTION; 10.1 MICROELECTROMECHANICAL SYSTEMS; 10.2
SEMICONDUCTOR MICROMACHINING BY EMM
10.3 MICROENGINEERING APPLICATIONS
REFERENCES; CHAPTER 11 -
ELECTROCHEMICAL MICROSYSTEM TECHNOLOGY; INTRODUCTION; 11.1
FEATURES OF EMST; 11.2 SCALING DOWN AND SCALING UP; 11.3
ELECTROCHEMICAL MICROCELL AND MICROELECTRODE; 11.4
ELECTROCHEMICAL REACTIONS IN EMST; 11.5 APPLICATIONS OF EMST
IN MICROSYSTEM TECHNOLOGY; REFERENCES; CHAPTER 12 - RECENT
ADVANCEMENTS IN EMM FOR MICRO AND NANOFABRICATION;
INTRODUCTION; 12.1 WIRE EMM; 12.2 SOLID-STATE EMM; 12.3
SURFACE STRUCTURING; 12.4 ELECTROCHEMICAL WET STAMPING; 12.5
ELECTROCHEMICAL PATTERNING BY ENFACE TECHNOLOGY; 12.6
NANOFABRICATION BY EMM
REFERENCES
